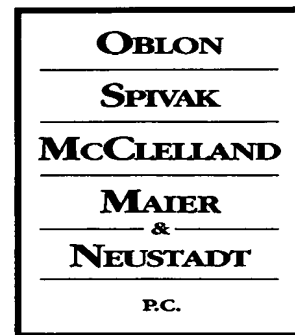


IFW



Docket No.: 247903US90CONT

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

RE: Application Serial No.: 10/773,293
Applicants: Tetsuo TANIGUCHI
Filing Date: February 9, 2004
For: EXPOSURE METHOD AND LITHOGRAPHY
SYSTEM, EXPOSURE APPARATUS AND METHOD
OF MAKING THE APPARATUS, AND METHOD OF
MANUFACTURING DEVICE
Group Art Unit: 2851
Examiner: NGUYEN, H.

SIR:

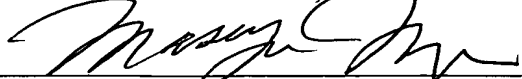
Attached hereto for filing are the following papers:

- Preliminary Amendment and Response to Restriction Requirement
- Information Disclosure Statement
- Form PTO 1449

Our credit card payment form in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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